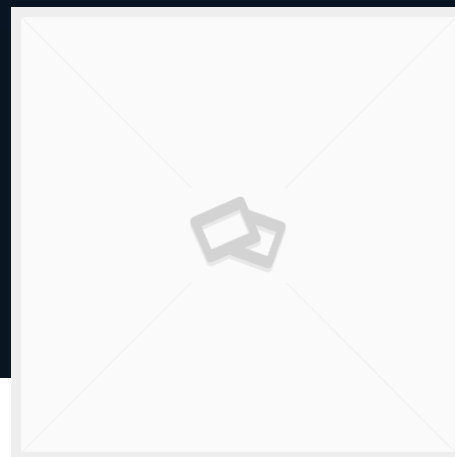


RADICAL PLASMA SOURCE (REMOTE PLASMA SOURCE) - MA2000C-233BB

Category: Plasma components



ADDITIONAL INFORMATION

Typ	Radical plasma source (Remote Plasma Source)
Process	Etching & Deposition
Output Connection Type	ISO-K 63
Dielectric material	Ceramics
Mains voltage nominal [V]	230 / 208
Output Power [W]	2000
Frequency [MHz]	2450